

MEASURED DATA DISPLAYING METHOD FOR EPMA

Patent Number: JP63318054
Publication date: 1988-12-26
Inventor(s): NIWA NAOMASA
Applicant(s): SHIMADZU CORP
Requested Patent: JP63318054
Application Number: JP19870153800 19870619
Priority Number(s):
IPC Classification: H01J37/22; G01N23/225
EC Classification:
Equivalents: JP2830875B2

Abstract

PURPOSE:To grasp the distribution state of an element on a sample face at real time by scanning an electron beam according to the information of the specified analysis positions along the desired curve on a sample with an input device such as a mouse or a track ball and scanning the raster of a CRT display synchronously with it.

CONSTITUTION:Analysis positions are specified along the desired curve on a sample 2 with an input device such as a mouse 18 or a track ball, and an electron beam is scanned according to the information of the specified analysis positions. The raster of a CRT display 14 is scanned synchronously with it, and the locus corresponding to the electron beam scan and the profile of the X-ray strength detected from the sample 2 using this locus as a base line are displayed on a screen. The distribution state of a specific element at the optional position can be thereby grasped at real time.

Data supplied from the **esp@cenet** database - I2